

**Model : NEFL - 309s**

- Process : (PE) CVD, Etcher, Asher
- Application : End Point Detection

**Features & Benefits**

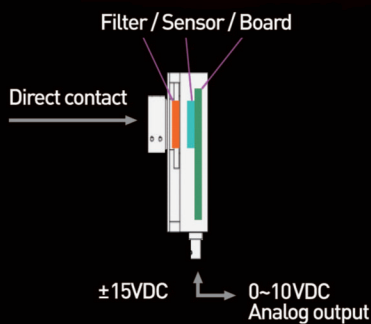
- In-Situ Process Monitor
- Filter Type(한 개의 파장 선택적 검출)
- 안정적인 기능 및 용이한 사용
- Asher 설비 모니터링에 최적화 된 Solution



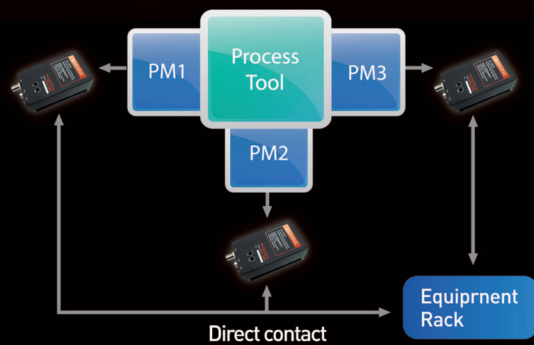
2014 Product Catalog VOL.1

End Point Detector **Filter Type EPD**  
Model NEFL Series

**CONSTRUCTION**



**CONFIGURATION**



**SPECIFICATION**

ITEM	DESCRIPTIONS
Resolution	10nm
Light Transmission	Direct contact on chamber window
Input Voltage	± 15 VDC
Output	0 ~ 10 VDC Analog Signal
Gain / Offset Value	Adjustable
Sensor	PMT or Enhanced detector
Operating Temperature	-10 ~ 60°C
Dimension	95(W) x 55.7(H) x 55(D) mm
Weight	About 0.3 ~ 0.8kg



## NANOTECH Product Group